



501.37854X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): T. NAKATA, et al

Serial No.: 09/437,265

Filed: November 10, 1999

For: METHOD FOR MEASURING DIMENSIONS AND ALIGNMENT  
OF THIN FILM MAGNETIC HEAD AND APPARATUS  
THEREFOR

Group: 2862

Examiner:

**PRELIMINARY AMENDMENT**

Assistant Commissioner for Patents  
Washington, D.C. 20231

April 18, 2000

Sir:

The following preliminary amendments and remarks are respectfully submitted in connection with the above-identified application.

**IN THE SPECIFICATION:**

Please replace the original specification with the attached Substitute Specification.

**IN THE CLAIMS:**

Please amend the claims as follows:

1. (amended) Method [for] of measuring dimensions and alignment of a thin film magnetic head to monitor a lapping process, including the steps of:

illuminating a magnetoresistance effect element and a